



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent application of :  
Yeong-Kwan KIM et al. : Group Art Unit 1762  
Serial No. 09/414,526 : Examiner M. Cleveland  
Filed October 8, 1999 :  
METHOD FOR MANUFACTURING A THIN FILM

#12/B  
Hqda  
8/30/01  
(NE)

AMENDMENT AFTER FINAL

Honorable Commissioner For Patents  
Washington, D.C. 20231

RECEIVED  
AUG 30 2001  
TC 1700

Sir:

July 11/11/01

In response to the final Office Action dated February 26, 2001, the period for response having been extended by a concurrently filed Petition For Extension Of Time, the following amendments and remarks are submitted:

In the Claims<sup>1</sup>

Kindly rewrite Claim 1 to read as follows:

1. (Twice amended) A method for manufacturing a thin film, comprising:

loading a substrate into a reaction chamber;

uniformly terminating dangling bonds on the surface of the substrate with

a specific atom;

chemically adsorbing a first reactant onto the terminated substrate by

injecting the first reactant into the reaction chamber;

<sup>1</sup> A copy of any revised claims showing additions and deletions thereto is attached as ATTACHMENT "A".